

[ABSTRACT]

SEMICONDUCTOR DEVICE MANUFACTURING DEVICE AND MANUFACTURING METHOD

A semiconductor device manufacturing device (10) includes a stage (12), an installing
5 head (14) that has a chip holding surface (26) and disposes a chip (100) on a substrate (110), a
measuring mechanism (16) that measures a tilt angle of the chip (100) loaded on an installing
surface (112) of the substrate (110) by the installing head (14) with respect to the installing
surface (112) as a detection tilt angle S_d , a holding surface adjusting mechanism (18) that
changes a holding surface tilt angle S_b which is a tilt angle of the chip holding surface (26) with
10 respect to a loading surface (21), and a controller (20) that calculates a correction amount C of
the holding surface tilt angle S_b based on the detection tilt angle S_d and changes the holding
surface tilt angle S_b by the holding surface adjusting mechanism (18) according to the calculated
correction amount C .

15 Figure 1